



Recent Advances in Micro/Nanofabrication and Optical Devices

Guest Editor:

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Deadline for manuscript submissions:

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Message from the Guest Editor

We are pleased to announce a Special Issue on the "Recent Advances in Micro/Nanofabrication and Optical Devices" in our journal. Micro/nanofabrication has been rapidly advancing in recent years, driven by the demand for smaller and more efficient devices in various fields such as electronics, photonics, and biotechnology.

The aim of this Special Issue is to present the recent advances in micro/nanofabrication and optical devices, including but not limited to novel micro/nanofabrication techniques, new optical devices, and emerging applications. The Special Issue will also explore the challenges and opportunities associated with the development of optical micro/nanofabrication and devices. Submissions should align with the scope of our journal and contribute to advancing the understanding of this field.

We look forward to receiving your contributions and publishing a collection of high-quality articles that will advance the field of optical micro/nanofabrication and devices.





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Editor-in-Chief

Message from the Editor-in-Chief

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